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## Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

## Listing of Claims:

1. (currently amended) A vacuum processing apparatus comprising:

~~a transfer unit disposed at a center thereof;~~

~~plural two~~ processing chambers disposed adjacent one another, each processing chamber having a processing table for supporting an object to be processed and carrying out processing using a gas;

a transfer unit coupled to said two adjacent processing chambers which transfers the object to be processed at least one of to and from at least one of said two adjacent processing chambers; and

~~a mass flow controller-controlling unit disposed interposed between said two adjacent of the plural processing chambers for directly supplying gas to each of said two adjacent the two of the plural processing chambers for enabling processing of the object to be processed when supported on the processing table thereof.~~

Claims 2 and 3 (canceled)

Claims 4 - 6 (canceled)

7. (currently amended) A vacuum processing apparatus according to claim 1, wherein the ~~two of the plural processing chambers are coupled to the transfer unit so as to be adjacent one another, and the mass flow controller-controlling unit is interposed~~ disposed between the said two adjacent of the plural processing

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chambers ~~which are adjacent one another~~ without being fluidly connected to the transfer unit.

8. (currently amended) A vacuum processing apparatus according to claim 7, wherein the mass flow ~~controller~~ controlling unit includes a first mass flow ~~control unit~~ controlling device for supplying gas to one of the said two adjacent processing chambers and a second mass flow ~~control unit~~ controlling device for supplying gas to another of the said two adjacent processing chambers, ~~the said first mass flow controlling device~~ and said second mass flow ~~controller units~~ controlling device being disposed with respect to one another in a vertical direction.

9. (currently amended) A vacuum processing apparatus according to claim ~~8~~ 1, wherein the said two adjacent processing chambers are detachably connected to the said transfer unit.

10. (currently amended) A vacuum processing apparatus comprising:

~~at least one processing chamber being subjected to a vacuum state for processing a wafer disposed therein, the at least one processing chamber being supplied with a processing gas to generate plasma which is utilized to process the wafer disposed therein;~~

~~wherein the at least one processing chamber includes two vacuum processing chambers disposed adjacent to one another and being detachably connected to the vacuum processing apparatus, the two adjacent vacuum processing chambers being supplied with a processing gas to generate plasma utilized for processing a wafer disposed therein; and~~

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plural controllers ~~for controlling which control~~ the supply of the processing gas directly into each of the two adjacent vacuum processing chambers so as to enable processing of the wafer disposed therein, the plural controllers being disposed between the two adjacent vacuum processing chambers ~~which are disposed adjacent one another~~.

11. (currently amended) A vacuum processing apparatus according to claim 10, further comprising a transfer ~~chamber-unit~~ for enabling transfer of the wafer, wherein the two adjacent vacuum processing chambers ~~being are~~ detachably connected to the transfer ~~chamber-unit~~ so as to enable transfer of the wafer between a respective vacuum processing chamber and the transfer-chamber unit.

12. (currently amended) A vacuum processing chamber according to claim 11, wherein the transfer ~~chamber-unit~~ has a polygonal shape in plan view, and each of the two adjacent vacuum processing chambers are disposed on respective side walls forming two adjacent sides of the polygonal shape of the transfer-chamber unit.

13. (currently amended) A vacuum processing apparatus according to claim 10, wherein the plural controllers are disposed adjacent one another in a vertical direction, one of the plural controllers directly supplying gas to one of the two adjacent vacuum processing chambers and the other of the plural controllers directly supplying gas to the other of the two adjacent vacuum processing chambers.

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14. (previously presented) A vacuum processing apparatus according to claim 10, wherein the plural controllers are disposed in a space between the two adjacent vacuum processing chambers.

15. (previously presented) A vacuum processing apparatus according to claim 13, wherein the plural controllers are detachable from the vacuum processing apparatus as one unit.

16. (currently amended) A vacuum processing apparatus according to claim 11, wherein the plural controllers are disposed adjacent one another in a vertical direction, one of the plural controllers directly supplying gas to one of the two adjacent vacuum processing chambers and the other of the plural controllers directly supplying gas to the other of the two adjacent vacuum processing chambers.

17. (previously presented) A vacuum processing apparatus according to claim 11, wherein the plural controllers are disposed in a space between the two adjacent vacuum processing chambers.

18. (previously presented) A vacuum processing apparatus according to claim 17, wherein the plural controllers are detachable from the vacuum processing apparatus as one unit.

19. (currently amended) A vacuum processing apparatus according to claim 12, wherein the plural controllers are disposed adjacent one another in a vertical direction, one of the plural controllers directly supplying gas to one of the two

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adjacent vacuum processing chambers and the other of the plural controllers directly supplying gas to the other of the two adjacent vacuum processing chambers.

20. (previously presented) A vacuum processing apparatus according to claim 12, wherein the plural controllers are disposed in a space between the two adjacent vacuum processing chambers.

Claim 21 (canceled)

Claim 22 (canceled)

23. (new) A vacuum processing apparatus according to claim 7, wherein said two adjacent processing chambers are detachably connected to said transfer unit.

24. (new) A vacuum processing apparatus according to claim 8, wherein said two adjacent processing chambers are detachably connected to said transfer unit.